## IN THE CLAIMS:

- 22. (currently amended) A gas flow sensor, comprising:
- a reference resistor element <u>comprised of an oxide electrically resistive</u>

  <u>material formed on a first electrically insulating substrate</u>:
- a flow-sensing resistor element comprised of said oxide electrically resistive material formed on a second electrically inculating substrate, wherein said-flow-sensing resistor is bested and said resister elements are formed of an exide electrically resistive material with a temperature coefficient of resistance between 2500 and 4500 ppm/°C; and

an electrical circuit coupled to said reference resistor element and said flow sensing resistor element, said electrical circuit responsive to a ratio in resistance between said reference oxide electrically resistive material and said flow sensing oxide electrically resistive material wherein said ratio in resistance is a function of a rate of gas flow over said materials, in electrical communication with said reference resistor element and said flow sensing resistor element.

- 23. (previously presented) The gas flow sensor according to claim 22, wherein said oxide electrically resistive material comprises a ruthenium containing oxide in a glassy matrix.
- 24. (previously presented) The gas flow sensor of claim 22 wherein a temperature of said reference resistor is substantially similar to a temperature of a gas flow flowing past said resistors.
- 25. (currently amended) The gas flow sensor of claim 24 wherein said electrical circuit further comprises a current source coupled to said flow sensing resistor and said electrical circuit is adapted to adjust a current flow from said current source to maintain a predetermined temperature differential resistance is maintained ratio between said flow-sensing resistor and said reference resistor.
- 26. (previously presented) The gas flow sensor of claim 22 wherein said gas is air.

- 27. (currently amended) The gas flow sensor of claim 22, further comprising: anwherein said electrical circuit is capable offer determining a resistance of said reference resistor and a resistance of said flow sensing resistor, wherein and a mass flow rate of said gas flow is a function of said resistances.
- 28. (previously presented) The gas flow sensor of claim 22 wherein said electrical circuit further comprises a current source coupled to said flow-sensing resistor element and said electrical circuit is capable of maintaining a target temperature differential between said reference resistor element and said flow-sensing resistor element by controlling an electrical current flow to said flow-sensing resistor element.

29-32. (withdrawn)

33. (currently amended) A gas flow sensor, comprising:

a reference resistor element <u>comprised of an oxide electrically resistive</u>

material formed on a first segment of an<u>attached</u> to a first portion of an

electrically insulating substrate <del>material and disposed in a gae flow without</del>

heating:

a flow sensing resistor element comprised of said oxide electrically resistive material and attached to a second portion of formed on a second segment of said electrically insulating substrate material and disposed in said gas flow, said flow sensing resistor element being heated to a temperature higher than the temperature of said reference resistor element, wherein said reference resistor element are formed of an oxide electrically resistive material with a temperature coefficient of resistance greater than 2500 ppm/°C; and

an electrical circuit in electrical communication with coupled to said reference resistor element and said flow sensing resistor element, said electrical circuit responsive to a ratio in resistance between said reference oxide electrically resistive material and said flow sensing oxide electrically resistive material wherein said ratio in resistance is a function of a rate of gas flow over said materials, said electrical circuit further comprising a current source coupled

to said flow sensing resistor and said electrical circuit is adapted to adjust a current flow from said current source to maintain a predetermined resistance ratio between said flow sensing resistor and said reference resistor.

- 34. (previously presented) The gas flow sensor according to claim 33, wherein said oxide electrically resistive material comprises a ruthenium containing oxide in a glassy matrix.
- 35. (previously presented) The gas flow sensor according to claim 33 wherein said ruthenium-containing oxide resistor elements comprises at least one of: Pb, Si and Bi.
- 36. (previously presented) The gas flow sensor according to claim 33, wherein said reference resistor has an electrical resistance at least 10 times the electrical resistance of said flow sensing resistor.
- 37. (previously presented) The gas flow sensor according to claim 33, wherein said reference resistor element and said flow sensing resistor element each have a thickness between 2 and 30 micrometers.
- 38. (previously presented) The gas flow sensor according to claim 33, wherein said reference resistor element and said flow-sensing resistor element each has a thickness between 5 and 20 micrometers.
- 39. (previously presented) The gas flow sensor according to claim 33 wherein said reference resistor element is formed in a serpentine configuration.
- 40. (previously presented) The gas flow sensor according to claim 33 wherein said reference resistor element is formed in a serpentine configuration having vertical segments connected by horizontal segments with an aspect ratio of length/width of the resistor being at least 2.

41. (previously presented) The gas flow sensor according to claim 33 wherein said electrical circuit maintains a target temperature differential between said reference resistor element and said flow-sensing resistor element by controlling an electrical current flowing to said flow-sensing resistor element.

## 42-46. (withdrawn)

- 47. (new) The gas flow sensor of claim 22 wherein said reference resistor element and said flow-sensing resistor element are coupled to an electrically insulating substrate.
- 48. (new) The gas flow sensor of claim 22 wherein said reference resistor element is coupled to a first electrically insulating substrate and said flow sensing resistor element is coupled to a second electrically insulating substrate.
- 49. (new) The gas flow sensor of claim 22 wherein said resistor elements have a temperature coefficient of resistance in the range of about 2600 to 3800 ppm/°C.
- 50. (new) The gas flow sensor of claim 33 wherein said first and second portions of said electrically insulating substrate are contiguous.
- 51. (new) The gas flow sensor of claim 33 wherein said first and second portions of said electrically insulating substrate are separated.
- 52. (new) The gas flow sensor of claim 33 wherein said resistor elements have a temperature coefficient of resistance in the range of about 2600 to 3800 ppm/°C.